



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/044,206  
Filing Date ..... January 11, 2002  
Inventor ..... Jerome Michael Eldridge  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... Laura M. Schillinger  
Attorney's Docket No. .... MI22-1914  
Title: Methods of Forming Void Regions, Dielectric Regions and Capacitor  
Constructions

**RESPONSE TO OCTOBER 21, 2003 FINAL OFFICE ACTION**

To: Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: Satheesh K. Karra (Tel. 509-624-4276; Fax 509-838-3424)  
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Responsive to the Office Action dated October 21, 2003, Applicant remarks  
as follows:

**AMENDMENTS**

**Claims** begin on page 2 of this paper.

**Remarks** begin on page 6 of this paper.

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